Special Issue

Advanced Machine Learning Algorithms for Biometrics and Its Applications

Message from the Guest Editors

Recently, advanced machine learning has received a great deal of attention in solving difficult and complex problems related to biometric recognition and security, where conventional machine learning techniques have shown their limitations.   This Special Issue aims to solicit original research papers, as well as review articles focusing on biometrics and its applications based on advanced machine learning algorithms. We are inviting original research works covering novel theories, innovative methods, and meaningful applications that can potentially lead to significant advances in the biometrics domain.   In addition, the authors of the papers which will be presented at the 4th International Workshop on "Recent Advances in Biometrics and its Applications" that we are organizing in conjunction with the 43rd International Conference on Telecommunications and Signal Processing (TSP) will be invited to submit an extended version of their papers to this Special Issue after the conference.

Guest Editors

Prof. Dr. Larbi Boubchir

Prof. Dr. Elhadj Benkhelifa

Prof. Dr. Boubaker Daachi

Deadline for manuscript submissions

closed (31 December 2021)

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About the Journal

Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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